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IEEE STD	IEEE Standard			13-15 Sept. 2005 Page(s):17 - 20 Digital Object Identifier 10.1109/ISSM.2005.1513285		
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		□	2.	The Virtual Fab the core of future technology development Torres, K.; Smith, E.; McDonald, C.; Rinn Cleavelin, C.; Advanced Semiconductor Manufacturing Conference and Worksho 8-10 Sept. 1999 Page(s):222 - 226 Digital Object Identifier 10.1109/ASMC.1999.798229	p, 1999 IEEE/SEMI	
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			3.	A dynamic binding model for service creation in virtual fab Shi-Chung Chang; Tsung-Lian Chou; Ruey-Shan Guo; Yea-Huey S Semiconductor Manufacturing Technology Workshop, 1998 16-17 June 1998 Page(s):131 - 138 Digital Object Identifier 10.1109/SMTW.1998.722674	Su; Ling-Ling Lu; I-Chang Lai	
			•	AbstractPlus   Full Text: PDF(296 KB)   IEEE CNF   Rights and Permissions		
			4.	Foundry technology and services Tsai, R.L.S.; Semiconductor Manufacturing Technology Workshop, 1998 16-17 June 1998 Page(s):139 Digital Object Identifier 10.1109/SMTW.1998.722678 AbstractPlus   Full Text: PDF(56 KB) IEEE CNF		
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			5.	Foundry technology for the next decade Sun, J.Y.C.; Shang-Yi Chiang; Liu, M.; Electron Devices Meeting, 1998. IEDM '98 Technical Digest., Intern 6-9 Dec. 1998 Page(s):321 - 324 Digital Object Identifier 10.1109/IEDM.1998.746364	national	
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